

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant	: Masahiko NAKAMORI, et al.
App. No	: 10/536,621
Filed	: May 26, 2005
For	: POLISHING PAD AND METHOD OF PRODUCING SEMICONDUCTOR DEVICE
Examiner	: Sylvia MaCarthur
Art Unit	: 1792
Conf No.	: 9275

**AMENDMENT ACCOMPANYING RCE****Mail Stop AF**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action, dated June 25, 2009, Applicant respectfully submits the following amendments and remarks in connection with the above-captioned application.

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper.

**Remarks** begin on page 5 of this paper.